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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Sylvia MacArthur

SUBSTRATE POLISHING APPARATUS
AND SUBSTRATE POLISHING METHOD

RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1763

AMENDMENT AFTER FINAL REJECTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of May 21, 2004, kindly amend the above-referenced
U.S. patent application as follows:

THE COMMISSIONER IS ADVISED
TO CHARGE ANY DELIVERY OF THIS
FEES FOR THIS PAPER TO BE POST
ACCOUNT NO. 23-0975